

# Letters

## 1.37 kV/12 A NiO/ $\beta$ -Ga<sub>2</sub>O<sub>3</sub> Heterojunction Diode With Nanosecond Reverse Recovery and Rugged Surge-Current Capability

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**Abstract**—Ga<sub>2</sub>O<sub>3</sub> power diodes with high voltage/current ratings, superior dynamic performance, robust reliability, and potentially easy-to-implement are a vital milestone on the Ga<sub>2</sub>O<sub>3</sub> power electronics roadmap. In this letter, a better tradeoff between fast reverse-recovery and rugged surge-current capability has been demonstrated in NiO/Ga<sub>2</sub>O<sub>3</sub> p-n heterojunction diodes (HJDs). With the double-layered p-NiO design, the HJD exhibits superior electrostatic performances, including a high breakdown voltage of 1.37 kV, a forward current of 12.0 A with a low on-state resistance of 0.26  $\Omega$ , yielding a static Baliga's figure of merit (FOM) of 0.72 GW/cm<sup>2</sup>. Meanwhile, the fast switching performance has been observed with a short reverse recovery time in nanosecond timescale (11 ns) under extreme switching conditions of  $di/dt$  up to 500 A/ $\mu$ s. In particular, for a 9-mm<sup>2</sup> HJD, a large surge current of 45 A has also been obtained in a 10-ms surge transient, thanks to the conductivity modulation effect. These results are comparable with those of the advanced commercial SiC SBDs and have significantly outperformed the past reported Ga<sub>2</sub>O<sub>3</sub> HJDs, fulfilling the enormous potential of Ga<sub>2</sub>O<sub>3</sub> in power applications.

**Index Terms**—Fast reverse recovery, Gallium oxide (Ga<sub>2</sub>O<sub>3</sub>), NiO, p-n heterojunction diode (HJD), surge current..

### I. INTRODUCTION

GALLIUM oxide (Ga<sub>2</sub>O<sub>3</sub>) materials have invoked great interest for power devices applications. The attractive properties of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, such as an ultrawide bandgap of  $\sim$ 4.8 eV and high breakdown electric field exceeding 8 MV/cm, boast  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> as a potential replacement of silicon for high-voltage

device technologies [1]–[3]. For such superior materials, the unipolar- and bipolar-power devices based on  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> are both highly desired for attractive high-power applications in electronic circuits [4], [5]. However, the absence of p-type Ga<sub>2</sub>O<sub>3</sub> directly hinders the rational design of bipolar devices [6]. Alternatively, bipolar Ga<sub>2</sub>O<sub>3</sub> diodes were realized by using a natively p-type oxide to produce p-n heterojunction diodes (HJDs) involving n-type Ga<sub>2</sub>O<sub>3</sub> [7]. Based on this advanced technology, the NiO/Ga<sub>2</sub>O<sub>3</sub> HJDs with excellent reverse blocking capability have been recently demonstrated, obtaining a high breakdown voltage (BV) of 1.86 kV [8] and an ultra-low reverse leakage current of below 1  $\mu$ A/cm<sup>2</sup> [9]. But, a surprising result is that the forward  $I$ - $V$  characteristics of the reported p-n HJDs are similar to those of unipolar Schottky barrier diode (SBD), presenting linear current conduction instead of bipolar behavior [8], [9]. As being demonstrated in SiC and GaN power diodes, with the bipolar conduction (or the conductivity modulation) from minority carrier injection, the devices not only have advantages in increasing the current density but also can reduce the on-state resistance, leading to a strong surge-current tolerance [10], [11]. Therefore, it is of great importance to identify whether the Ga<sub>2</sub>O<sub>3</sub> p-n HJDs are capable of conductivity modulation in the forward bias region, especially during high surge-current operation. The injection and storage of holes in the drift layer may also significantly degrade the dynamic switching performance, due to the minority carrier's recombination/ extraction [12]. Thus, dynamic switching and surge-current performance in Ga<sub>2</sub>O<sub>3</sub> HJDs worth specific investigations.

In this letter, with the construction of double-layered p-NiO with  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, the large-area (1-mm<sup>2</sup>) vertical NiO/Ga<sub>2</sub>O<sub>3</sub> HJD exhibits a high BV of 1.37 kV, a forward current of 12.0 A, low on-state resistance of 0.26  $\Omega$ , yielding a static Baliga's figure of merit (FOM) of 0.72 GW/cm<sup>2</sup>. Furthermore, the 9-mm<sup>2</sup> HJDs deliver a record-high current of 70 A (10-ms surge current of 45 A) and a low on-state resistance ( $R_{on}$ ) of 65 m $\Omega$ , with simultaneously a BV of 462 V. Both devices clearly demonstrate the forward conductivity modulation characteristics and inherent reverse blocking capability of the p-n junction. In particular, by implementing these diodes into the board-level inductive switching circuits, ultra-fast switching performance has been observed, presenting a short reverse recovery time of 11 ns with low switching FOM) of 0.85  $\Omega$ ·nC. This letter, thus, clearly

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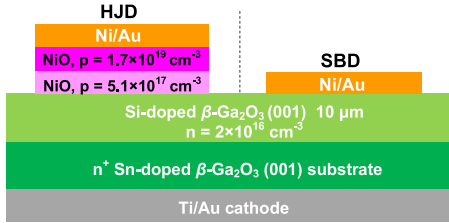


Fig. 1. (a) Schematics cross-section of vertical NiO/ $\beta$ -Ga<sub>2</sub>O<sub>3</sub> HJD (left) and Ni/ $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD (right).

demonstrates the notable potentials of the NiO/Ga<sub>2</sub>O<sub>3</sub> HJDs in high-power and high-speed switching applications.

## II. DEVICE FUNDAMENTALS

Fig. 1 shows the schematic cross-section view of the double-layered NiO/ $\beta$ -Ga<sub>2</sub>O<sub>3</sub> p-n HJD on highly conductive Sn-doped (001)  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> substrate by hydride vapor phase epitaxy, which consists of 10- $\mu$ m Si-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> drift layer with an electron concentration of  $2 \times 10^{16}$  cm<sup>-3</sup>, determined by Hall measurement at room temperature. The device process begins with the formation of back-side ohmic contact (cathode) of Ti/Au (20/80 nm) deposited by electron beam evaporation, followed by rapid thermal annealing at 500 °C for 1 min under the N<sub>2</sub> ambient. Subsequently, double-layered p-NiO films are deposited on the drift layer by the radio frequency (RF) magnetron sputtering technique. The RF power is 150 W, and the target is high purity (99.99%) NiO ceramics. More detailed descriptions of the double-layered NiO deposition have been given in our previous work [8]. The Hall measurement characterizations of the double-layered p-NiO films indicate that the 300-nm-thick bottom-side layer and a 100-nm-thick upper-side layer have hole concentrations and mobility of  $5.1 \times 10^{17}$  cm<sup>-3</sup>,  $0.94$  cm<sup>2</sup>/V·s and  $1.7 \times 10^{19}$  cm<sup>-3</sup>,  $0.3$  cm<sup>2</sup>/V·s, respectively. Finally, a Ni/Au (300/300 nm) metal stack is deposited on the upper p-NiO layer to form the ohmic contact (anode). Meanwhile, the Ni/ $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD is also fabricated on the same wafer by identical processes except for the p-NiO deposition underneath the Schottky anode metal.

## III. RESULTS AND DISCUSSION

### A. Static Characteristics

The 1-mm<sup>2</sup> devices encapsulated in TO-220 package are measured using a B1505 power device analyzer in the dc mode. As shown in Fig. 2(a), both the HJD and SBD exhibit a high on/off current ratio of  $10^8$  with a low subthreshold slop (SS) of  $\sim 68$  mV/dec, which are comparable with the state-of-art  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBDs with the implanted edge termination [13]. Meanwhile, the HJD exhibits a turn-ON voltage ( $V_{on}$ ) of 1.73 V, which is lower than the built-in potential ( $V_{bi}$ ) of 2.4 V for p-n heterojunction determined from the intercept of  $1/C^2$ -V plot on the  $x$ -axis [see Fig. 2(b)]. This phenomenon is also observed in Ni/ $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD with a lower  $V_{on}$  of 0.8 V but a higher  $V_{bi}$  of 1.2 V. It can be understood that electrons from the conduction band of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> are transferred into valance band of NiO or energy level of Ni mediated by defective states at the large-area interface [14]. The

low  $V_{on}$  is, therefore, available to Ga<sub>2</sub>O<sub>3</sub>-based HJDs, which is smaller than GaN p-n diodes with a  $V_{on}$  of  $\sim 3$  V [11], thus remarkably reducing the conduction losses.

To evaluate the current capability of the 1-mm<sup>2</sup> HJD and SBD, the pulsed  $I$ - $V$  measurements are carried out with a pulse width of 50  $\mu$ s and a duty cycle of 1% [see Fig. 2(c)] [1], where a high current rectifying level up to 12 A is obtained in both devices. Apparently, the HJD exhibits a continuous reduction of differential  $R_{on}$  from  $>20$  to  $0.26 \Omega$  with increased forward bias, while  $R_{on}$  of the SBD almost keeps a constant value of  $0.58 \Omega$ . The significant reduction of  $R_{on}$  with a nonlinearity  $I$ - $V$  characteristic is resulted from the onset of conductivity modulation by the minority carrier injection from the p-type NiO layer, enabling additional electrons accumulated in the drift region and improving the bipolar current spreading in vertical structures. It is noted that the  $I$ - $V$  characteristics of HJD are also different from the typical silicon-based bipolar diodes, which may be originated that, the bipolar conduction mode in the NiO/Ga<sub>2</sub>O<sub>3</sub> HJD is incipiently activated with the limited minority carrier injection at room temperature due to the larger valence band offset at NiO/Ga<sub>2</sub>O<sub>3</sub> interface and the relatively low hole mobility in NiO. In unipolar rectifiers, it has been reported that the decreased electron mobility induced by thermally enhanced phonon scattering could lead to severe  $R_{on}$  degradation at high temperatures. On the contrary,  $R_{on}$  of the bipolar device (such as GaN p-n diodes) increases much slower or even decreases with elevated temperatures, benefiting from the conductivity modulation effect [11]. Indeed, as shown in Fig. 2(d) and (e), with the temperature ( $T$ ) rising from 25 to 175 °C, the  $R_{on}$  of HJD was first reduced from 1.06 to 0.77  $\Omega$  and then stabilizes at 0.80  $\Omega$ , exhibiting a  $T$ -independent  $R_{on}$  behavior as similar in GaN p-n diodes [11], while that of SBD increases monotonically with a positive temperature coefficient of 2 m $\Omega$ /°C. Additionally, the values of  $V_{on}$  are reduced with elevated temperatures, which are primarily originated from the bandgap narrowing effect and thermally-enhanced carrier diffusion. Combining the merits of  $T$ -independent  $R_{on}$ , high BV and low  $V_{on}$ , the Ga<sub>2</sub>O<sub>3</sub> HJDs are highly desirable for high-power and high-temperature applications.

Fig. 2(f) shows the reverse  $I$ - $V$  characteristics of the HJD and SBD. Compared with the SBD with a BV of 245 V, the HJD exhibits a remarkably reduced leakage current with  $>10^6 \times$  lower in magnitude at considerable bias and an enhanced BV of 1370 V, yielding a static Baliga's FOM ( $BV^2/R_{on}$ ) of 0.72 GW/cm<sup>2</sup>. To our best knowledge, the achieved BFOM value is highest among the reported Ga<sub>2</sub>O<sub>3</sub> HJDs [8], [15] and comparable to the state-of-the-art Ga<sub>2</sub>O<sub>3</sub> SBDs [1], [3], [16]. The BV vs  $R_{on}$  of the large-area HJD is also benchmarked with the commercial 650 and 1200-V SiC SBD (C3D02065E, C4D02120A) [see Fig. 2(g)]. Additionally, a high on/off switching ratio of  $10^7$  ( $\sim 10$  A at +9 V/ $\sim 10^{-6}$  A at -900 V) has also demonstrated a reliable rectification capability of Ga<sub>2</sub>O<sub>3</sub> HJD.

### B. Switching Performance

For the practical high-power switching applications, current levels of Ga<sub>2</sub>O<sub>3</sub> diodes need to be as high as possible. To this end, the larger area (9-mm<sup>2</sup>) Ga<sub>2</sub>O<sub>3</sub> diodes have been fabricated

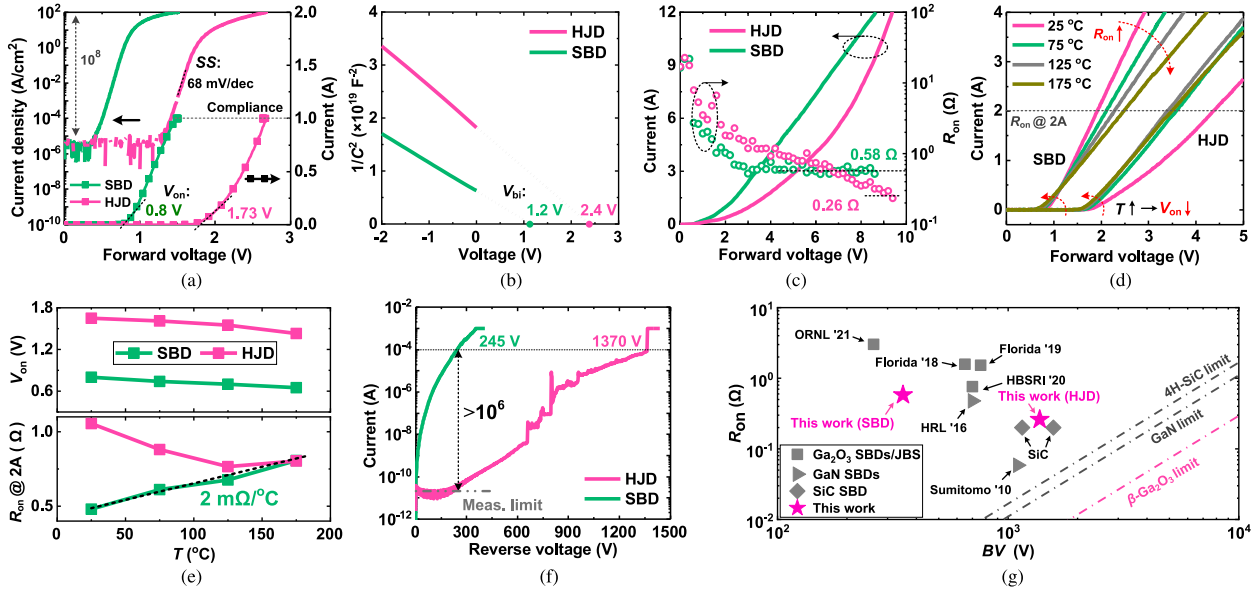


Fig. 2. (a) Forward dc  $I$ - $V$  characteristics of the 1-mm<sup>2</sup> HJD and SBD in log scale and linear scale. (b)  $1/C^2$  versus voltage during pulsed current measured at 100 kHz. (c) Pulsed  $I$ - $V$  characteristics and corresponding  $R_{on}$ . (d)  $T$ -dependent forward current at temperatures of 25, 75, 125, and 175 °C. (e)  $T$ -dependent  $V_{on}$  and  $R_{on}$ . The  $R_{on}$ s are extracted at forward current of 2 A. (f) Reverse  $I$ - $V$  characteristics. (g)  $R_{on}$  vs.  $BV$  of this vertical Ga<sub>2</sub>O<sub>3</sub> HJD/SBD, benchmarked with the state-of-the-art  $\sim$ 1-mm<sup>2</sup> Ga<sub>2</sub>O<sub>3</sub> SBDs/JBS, GaN SBDs, and commercial SiC SBD.

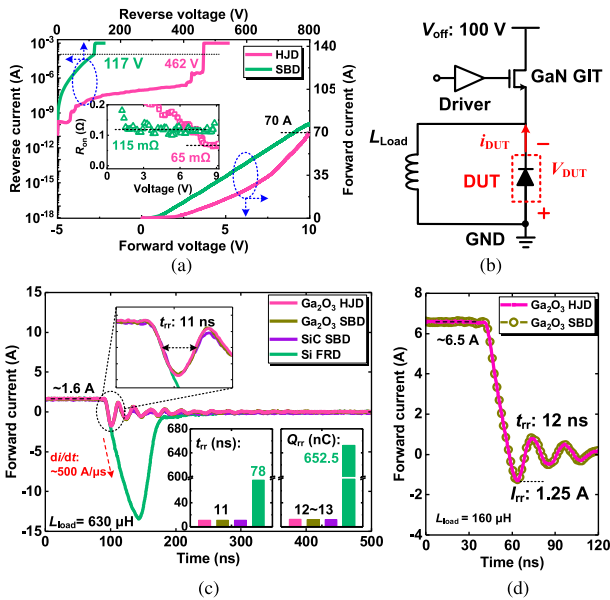


Fig. 3. (a) Reverse  $I$ - $V$  characteristics of 9-mm<sup>2</sup> Ga<sub>2</sub>O<sub>3</sub> diodes. Inset: The extracted  $R_{on}$  from forward  $I$ - $V$  measurements. (b) Schematic of the DPT circuit. The fast-speed commercial GaN gate injection transistor has been used as a control switch. (c) Reverse recovery characteristics of different diodes. Inset: Corresponding  $t_{Tr}$  and  $Q_{Tr}$ . The  $t_{Tr}$  is defined as the time when the reverse current recovers to 10% of its peak value, where the  $Q_{Tr}$  is calculated by the time-integration of reverse current. (d) Reverse recovery waveforms with a high forward current of  $\sim$ 6.5 A.

by extending the area of square anode contacts, which exhibits a highest recorded pulsed current of 70 A among the reported Ga<sub>2</sub>O<sub>3</sub> diodes [see Fig. 3(a)]. Moreover, such HJD delivers a BV of 462 V with a low leakage current of 0.1  $\mu$ A at  $-400$  V, outperforming the SBD with a BV of 117 V. Meanwhile, an

ultra-low  $R_{on}$  of 65 m $\Omega$  has been achieved, indicating the highly uniform current distribution within the large-area HJD.

To evaluate the dynamic switching performance of Ga<sub>2</sub>O<sub>3</sub>-based HJDs, board-level double-pulse-test (DPT) measurements have been performed [17] and the schematic circuit is shown in Fig. 3(b). For a forward conducting rectifier with a high current, a large amount of free carriers are injected into the drift layer. When the device under test (DUT) is switched from on-state to off-state, the stored charges must be fully removed before the build-up of the depletion region to withstand the reverse bias, leading to a reverse recovery process. As shown in Fig. 3(c), under a switching condition from a high forward current ( $i_{DUT}$ ) of 1.6 A to a reverse bias of 100 V with a fast  $di/dt$  of 500 A/ $\mu$ s, the 9-mm<sup>2</sup> HJD exhibits the superior switching performance with a reverse recovery time ( $t_{Tr}$ ) of 11 ns and a reverse recovery charge ( $Q_{Tr}$ ) of 13 nC, which is comparable with that of the commercial SiC SBD and presents apparently lower switching loss than the Si fast-recovery diode (FRD, RF305BM6S). Moreover, the switching FOM ( $R_{on} \times Q_{Tr}$ ), which is a merit for demonstrating high-speed switching capability, is only 0.85  $\Omega$ ·nC [17], [18]. Additionally, the small-area 1-mm<sup>2</sup> HJD also exhibits fast switching performance with low reverse recovery losses, when suffering from  $i_{DUT}$  of 5 A to a reverse bias of 600 V. These results clearly present the significant potentials of Ga<sub>2</sub>O<sub>3</sub> HJD in fast switching operations [19].

By decreasing the load inductor ( $L_{load}$ ) from 630 to 160  $\mu$ H in DPT circuit, a higher  $i_{DUT}$  of  $\sim$ 6.5 A (almost equal to the rated current  $i_{rated} \sim$ 6.2 A of [3] with the same 9-mm<sup>2</sup> area) is obtained [20], as present in Fig. 3(d). Even when switching from a high forward current, the HJD still shows almost zero-reverse-recovery characteristics with a low  $t_{Tr}$  of 12.0 ns. It should be noted that Ga<sub>2</sub>O<sub>3</sub> HJD and SBD exhibit similar switching behaviors regardless of  $i_{DUT}$ . The fast-speed recovery characteristic

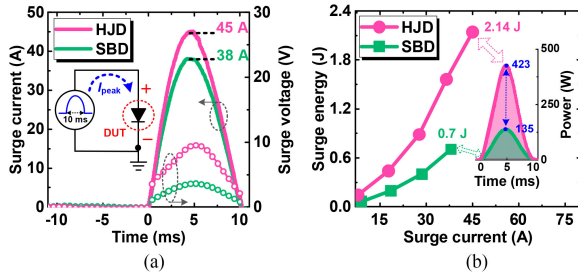


Fig. 4. (a) Surge current and voltage waveforms of the 9-mm<sup>2</sup> HJD and SBD. Inset: The resonance circuit generates a 10-ms half-sine surge current pulse to go through the DUT. (b) Corresponding surge power and energy.

of HJD may be attributed to the short minority-carrier lifetime ( $\tau_{HL}$ ) of p-n diodes at high-level injection. In terms of  $\tau_{HL} = 2 \times (I_{TR}/i_{DUT}) \times t_{TR}$  [15], the  $\tau_{HL}$  is determined to be 4.5 ns, which is comparable with the previously reported values [15] and is 70% lower than the  $t_{TR}$ . Moreover, the normalized  $Q_{TR}$  per device area for the HJD is only  $1.3 \times 10^{-7}$  C/cm<sup>2</sup> during the switching process. The low minority-carrier-stored charge in the drift region is mainly limited by the high barrier height, which could be induced by a large valence band offset of 3.6 eV at NiO/Ga<sub>2</sub>O<sub>3</sub> heterojunction [14]. With a short minority carrier lifetime, the stored charges are expected to be rapidly removed during the turn-off process of carrier sweep-out and fast recombination, revealing the intrinsic immunity of Ga<sub>2</sub>O<sub>3</sub> HJD to high current switching.

### C. Surge Current Ruggedness

With a long-duration high current conducting or at current overshoot/oscillation surging, a huge amount of Joule heat generated within the resistive diodes would lead to an abrupt rise of the junction temperature ( $T_j$ ) [21], [22], which, in turn, cause increased  $R_{on}$  and heat accumulation inside the diodes [23], consequently deteriorating the device performance. Therefore, sustaining the low  $R_{on}$  under the high current conducting condition is directly meaningful for enhancing the surge current capability. Recently, advanced double-side-cooled package strategies to weaken the temperature dependence of the  $R_{on}$  have been demonstrated in 9-mm<sup>2</sup> Ga<sub>2</sub>O<sub>3</sub> SBDs [3], successfully boosting the maximum surge current ( $I_{peak}$ ) from 37.5 to >60 A in a 10-ms duration. By using a similar resonance circuit to generate a half-sinusoidal surge current [3], the 9-mm<sup>2</sup> Ga<sub>2</sub>O<sub>3</sub> SBD with standard TO-220 package in this letter can also withstand a comparable  $I_{peak}$  of 38 A ( $T_j > 600$  K), as present in Fig. 4(a). Moreover, under the identical test conditions, a higher  $I_{peak}$  of 45 A is achieved, demonstrating apparently advantageous surge current tolerance of the Ga<sub>2</sub>O<sub>3</sub> HJD. Such enhanced surge capability is attributed to the  $T$ -independent  $R_{on}$  with a rather lower value at a high current level owing to the conductivity modulation effect, whereas the positive temperature coefficient of  $R_{on}$  in the SBD results in the severe self-heating effect and, thus, a lower surge current [11]. In particular, with the recorded surge current and voltage waveforms in a 10-ms duration, the corresponding device power and energy dissipation are calculated and summarized in Fig. 4(b). In both diodes, the surge

energy is observed to increase with elevated surge current. It is noted that the HJD withstands a higher surge power of 423 W with sustained energy of 2.14 J, which outperforms the SBD counterpart (135 W, 0.7 J). Thus, it is safe to conclude that the Ga<sub>2</sub>O<sub>3</sub> HJD is a better candidate for high-reliability power applications.

## IV. CONCLUSION

With the double-layered p-NiO design, large-area 1-mm<sup>2</sup>/9-mm<sup>2</sup> NiO/ $\beta$ -Ga<sub>2</sub>O<sub>3</sub> p-n HJDs have been demonstrated, yielding a high BV of 1370 V/462 V, a low  $R_{on}$  of 260/65 m $\Omega$ , and a record-high current of 12 A/70 A, respectively. In particular, ultra-fast switching performance with a reverse recovery time of 11 ns is achieved while maintaining a rugged surge-current tolerance with a surge-current of 45 A. Together with the advantage of high voltage/current ratings, high dynamic performance, high reliability and potentially easy-to-implement, the vertical Ga<sub>2</sub>O<sub>3</sub> HJDs present significant potentials in high-power, high-speed, and highly reliable power applications.

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